

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: 1112

Examiner: To Be Assigned

In Re PATENT APPLICATION Of:

Applicant(s) : LIU et al.

Serial No. : 08/958,460

Filed : October 28, 1997

For : HIGH DENSITY PLASMA  
CHEMICAL VAPOR DEPOSITION  
PROCESS

Attorney Ref.: JIA 462

STATUS REQUEST

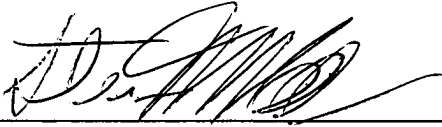
Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

Please let us know the status of the above-identified application and when an  
Action may be expected.

Respectfully submitted,

Date: 8/2/1999

  
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SMR/bec

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acted on 8/19/99.

  
RABON SERGENT  
PRIMARY EXAMINER

FEE ENCL. \$0  
Please charge any further  
fee to our Deposit Account  
No. 18-0002

#1/State  
Report  
8/31/99  
O'Brien  
AUG 02 1999  
PATENT & TRADEMARK OFFICE